

IN THE SPECIFICATION

Immediately below the title of the invention, please insert the following section on page 1:

CROSS REFERENCE TO RELATED APPLICATION

This application is based on Patent Application No. 2002-348903 filed in Japan on November 29, 2002, the contents of which are incorporated hereinto by reference.

Please replace the sub-heading at page 15, line 18 with the following:

DESCRIPTION OF THE ~~PREFERRED EMBODIMENTS~~ INVENTION

Please replace the paragraph on page 27, lines 9 to 21 with the following:

As shown in Figure 9, the height of the elevatable table 33 is adjusted such that the substrate accommodating trays 10 are engaged with the engaging claws 32f provided on the tray side engaging members 32c, except for the lowest substrate accommodating tray 10. In other words, the lowest substrate accommodating tray 10 is not engaged with the engaging claws 32f. When the height of the elevatable table 33 is thus adjusted, the hydraulic cylinders 32e on the upper surface of the supporting base 31 are driven in synchronization with each other, such that the three tray side engaging members 32c on one

support **32b** and the three tray side engaging members **32c** on the other support **32b** move toward the substrate accommodating trays **10**.

Please replace the paragraph on page 28, lines 9 to 17 with the following:

Then, the elevatable table **33** is moved down by the elevating unit **35**. The lowest substrate accommodating tray **10** on the table section **33a** is also moved down (i.e., the support pins **34** are moved up with respect to the lowest substrate accommodating tray **10**). While the elevatable table **33** is moved ~~down~~, down, the support pins **34** provided inside the supporting base **31** go through the lattice table section **33a** and are inserted into the openings **11a** of the bottom section **11** of the lowest substrate accommodating tray **10**.

Please replace the paragraph on page 39, lines 8 to 15 with the following:

As described above, the substrate transfer apparatus **30** according to the present invention can place, ~~with~~ with high efficiency, the glass substrates **20** in the substrate accommodating trays **10** stacked vertically. Since the substrate accommodating trays **10** are stacked vertically while

accommodating the glass substrates 20, the work efficiency of
accommodating the glass substrates 20 is significantly improved.